

Title: APPARATUS METHODS FOR CONTROLLING WAFER TEMPERATURE IN
CHEMICAL MECHANICAL POLISHING

Inventor: Nicolas Bright Application No, 10/722,839 Docket: LAM2P318D

Sheet 6 of 9 Replacement Sheet

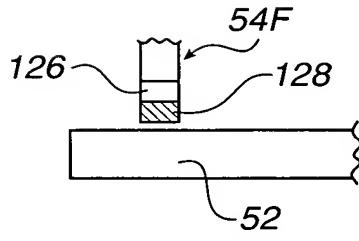
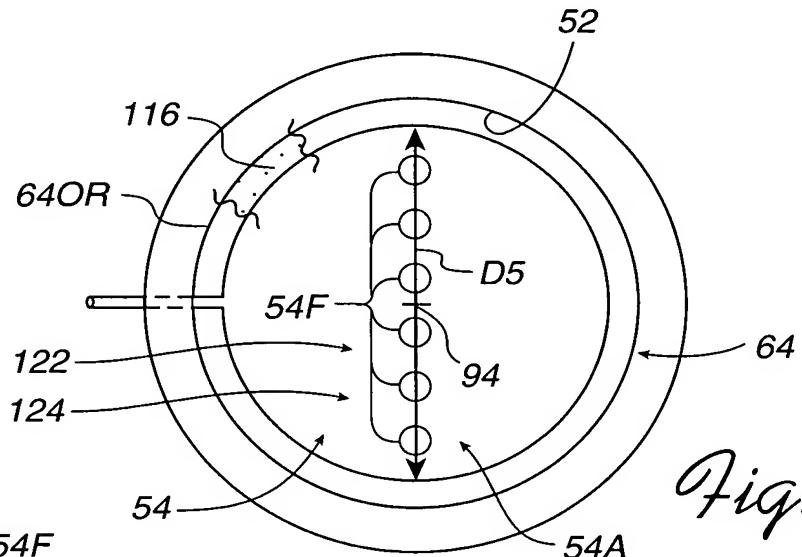


Fig. 5D

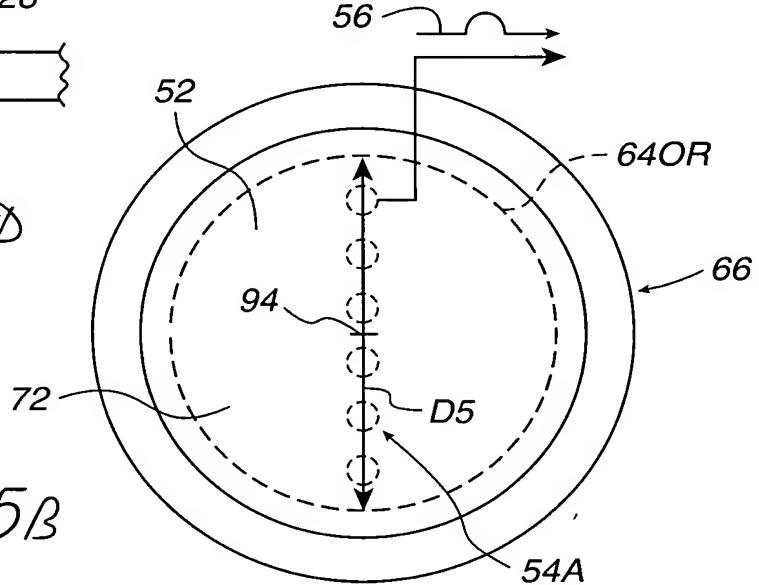
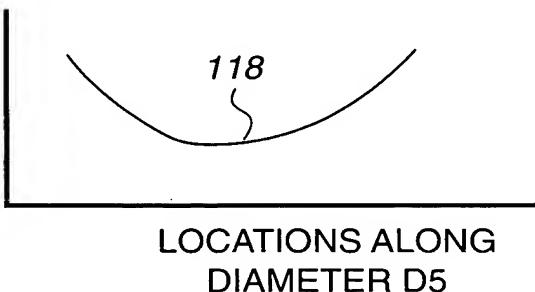


Fig. 5B

TEMPERATURE

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Fig. 5C



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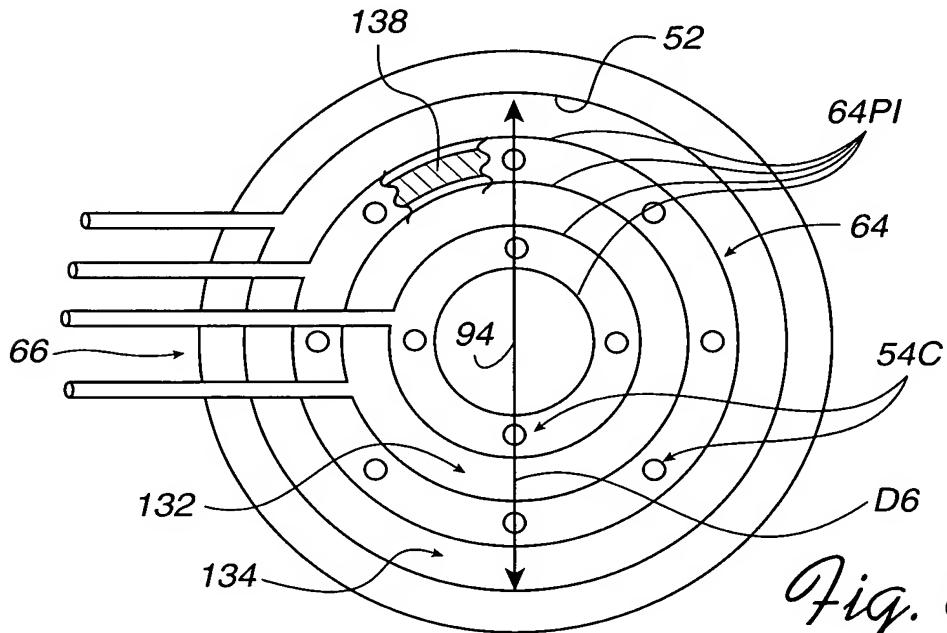


Fig. 6A

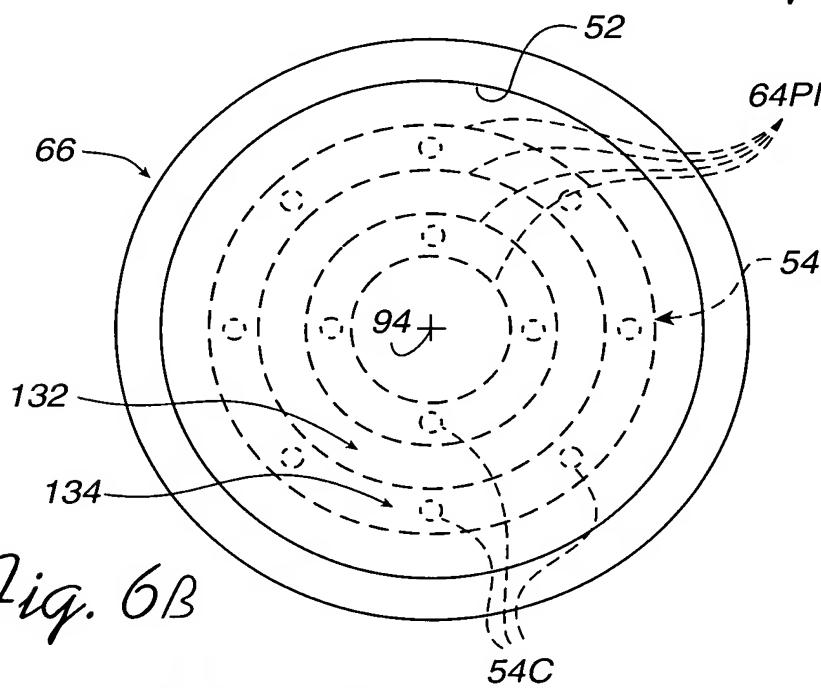


Fig. 6B

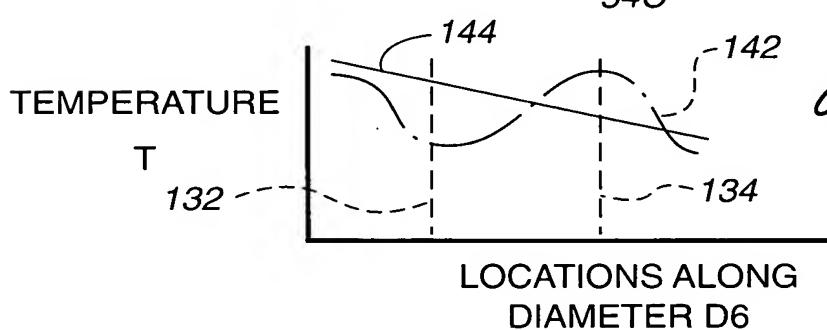


Fig. 6C